**Claims:**

1. A system for cleaning component parts in a cleaning chemistry comprising:

a wet bench set-up comprising:

a cleaning vessel assembly for holding one or more component parts to be cleaned during a cleaning process; and

a detachable cleaning cart detachably coupled with the cleaning vessel assembly for supplying one or more cleaning chemistries to the cleaning vessel assembly during the cleaning process.

2. The system of claim 1, wherein the component part is a showerhead.

3. The system of claim 1, wherein the wet bench set-up further comprises:

a frame which forms an overflow basin for holding the cleaning vessel assembly and capturing any fluids which may overflow from the cleaning vessel assembly during processing; and

a sink drain line for removing any fluids captured by the overflow basin during cleaning.

4. The system of claim 1, wherein the cleaning vessel assembly comprises:

a first cleaning basin for supporting a first component part to be cleaned;

a transducer positioned below the first cleaning basin,

a support positioned within the cleaning basin for supporting the component part to be cleaned.

5. The system of claim 4, wherein the cleaning vessel assembly further comprises:

a second cleaning basin for supporting a second component part to be cleaned

6. The system of claim 4, wherein the detachable cleaning cart comprises:

a system controller for controlling the cleaning process; and

a cleaning fluid supply module for supplying and recycling cleaning fluid to the cleaning vessel assembly.

7. The system of claim 6, wherein the cleaning fluid supply module comprises:

an inert gas module for supplying an inert gas which may be used as a purge gas during the cleaning process;

a deionized (DI) water supply module for supplying deionized water during the cleaning process; and

a first cleaning fluid supply tank for supplying cleaning fluid to the first cleaning basin.

8. The system of claim 7, wherein the cleaning fluid supply module comprises:

a second cleaning fluid supply tank for supplying cleaning fluid to the second cleaning basin.

9. The system of claim 6, wherein the system controller comprises at least one of the following: a PhotoMeghelic meter, a leak alarm for detecting leaks within the detachable cleaning cart, a programmable logic controller for controlling the overall cleaning system, and an in-line heat controller.

10. A method for cleaning component parts in a cleaning chemistry comprising:

providing a cleaning vessel assembly for holding one or more component parts to be cleaned during a cleaning process, comprising:

an outer cleaning basin;

a first cleaning basin circumscribed by the outer cleaning basin;

a second cleaning basin circumscribed by the outer cleaning basin; and

a transducer positioned within the outer cleaning basin below the first cleaning basin and the second cleaning basin;

providing a detachable cleaning cart detachably coupled with the cleaning vessel for supplying one or more cleaning chemistries to the cleaning vessel assembly during the cleaning process, comprising:

an inert gas module for supplying an inert gas which may be used as a purge gas during the cleaning process;

a deionized (DI) water supply module;

a first cleaning fluid supply tank for the first cleaning basin; and

a second cleaning fluid supply tank for the second cleaning basin;

positioning a first component part in the first cleaning basin;

positioning a second component part in the second cleaning basin;

flowing a first cleaning fluid from the first cleaning fluid supply tank into the first cleaning basin;

flowing a second cleaning fluid from the second cleaning fluid supply tank into the second cleaning basin;

cycling the transducer on and off to agitate the first cleaning fluid and the second cleaning fluid; and

flowing DI water from the DI water supply module into the first cleaning basin and the second cleaning basin to purge the first cleaning fluid from the first cleaning basin and the second cleaning fluid from the second cleaning basin.

11. The method of claim 10, wherein flowing a first cleaning fluid from the first cleaning fluid supply tank into the first cleaning basin and flowing a second cleaning fluid from the second cleaning fluid supply tank into the second cleaning basin occur simultaneously.

12. The method of claim 10, wherein flowing a first cleaning fluid from the first cleaning fluid supply tank into the first cleaning basin and flowing a second cleaning fluid from the second cleaning fluid supply tank into the second cleaning basin occur sequentially.

13. The method of claim 10, wherein the first cleaning fluid and the second cleaning fluid are different chemistries.

14. The method of claim 10, further comprising:

detaching the cleaning cart from the cleaning vessel;

moving the cleaning cart to a second cleaning vessel assembly; and attaching the cleaning cart to the second cleaning vessel assembly.

## CLAIMS

1. An invention not claimed in any divisional application.